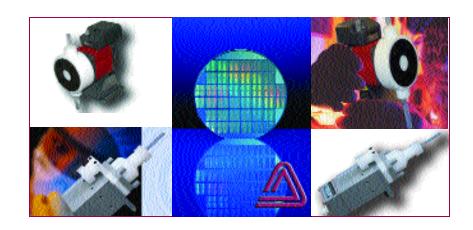
Metering, Dosing & Blending PUMPS



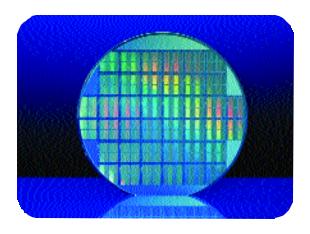
for the SEMICONDUCTOR INDUSTRY



IWAKI WALCHEM provides fluid handling solutions to the Semiconductor equipment industry. High purity metering pumps are provided for ontool chemical generation and chemical concentration management. As the leader in surface preparation recirculation pumps, our high purity pumps are the choice for CMP, etch/strip, and copper solution handling.

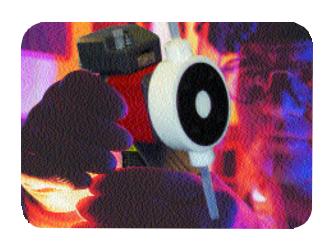
Metering - IW's metering pumps are positive displacement chemical dosing devices with the ability to vary capacity manually or automatically as process conditions require. This allows accurate mixing, blending or replenishment of ultra-high purity fluids.

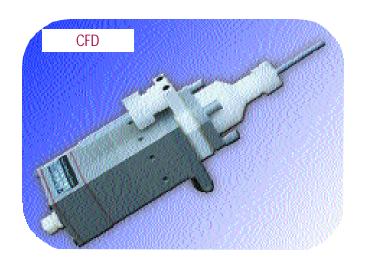


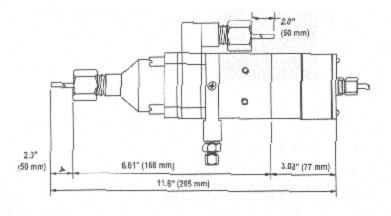


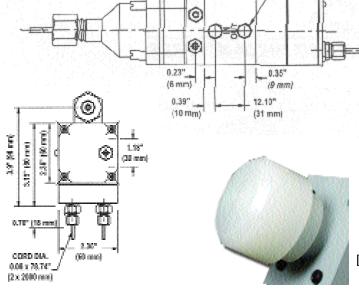
Dosing - The air-operated CFD is ideal for on-tool chemical generation such as SC-1, SC-2, dilute RCA cleans, buffered oxide etches and semiaqueous cleaning solutions. Added features such as sensors on the pneumatic drive and leak detection are standard.

HIGH PURITY - Our pumps are designed for the highest purity applications in the world. If parts per billion and parts per trillion ionic purity determine the success of your process, then look no further. Iwaki Walchem pumps are proven in both semiconductor and electronics grade chemical manufacturing.









CFD Series Chemical Dispensing Pump

High Purity Materials PTFE and PFA wetted parts and clean room manufacturing ensure process purity.

Highly Accurate Capable of 1% repeatability which translates into efficient use of chemistry and fast replenishment without overshoot.

Process Purity Ensured by integral leak detection sensor.

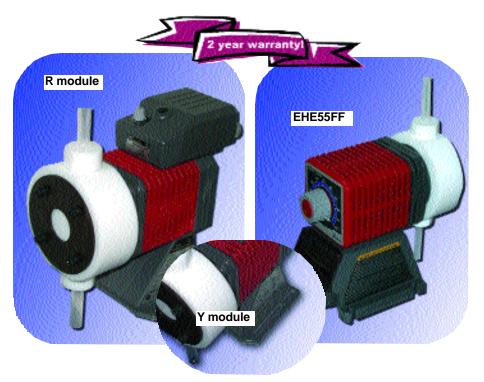
Easy Installation Suction and discharge double ball check valves reduce the number of fittings and make installation easy.

Easy Integration Integration with existing process controllers is simple.

Displacement Adjustment Knob

Series	Maximum Discharge Pressure psi (MPa)	Capacity* mL/stroke	Maximum Stroke Speed spm	Air Supply Pressure psi (MPa)	Wet End Material
CFD	7.1 (0.05)	6-10	30	21.3 to 42.7 (0.15 to 0.3)	PTFE/PFA

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Featuring Two Control Options

EHC35FF(R) series pumps come equipped with a speed control knob, digital pulse input and external start/stop functions.

EHC35FF(Y) series pumps can come equipped with digital speed control, programmable 4-20mA input and pulse input with multiplier divider. The Y module increases the turndown ratio on the EH-FF35 from 125:1 to 900:1. The Y module features a 12vdc power supply which allows you to use either a Hall Effect or reed switch flow meter.

Y Module Features

Microprocessor-Based Circuitry

Allows operator adjustment of pump speed and external input settings via 4-button keypad. External Digital Input Mode-Pulse Multiply Often used in flow propor-

Often used in flow proportional systems, such as flowmeter contactor or batch feed applications. One input pulse can produce 1 to 999 pump strokes.

External Digital Input Mode-Pulse Divide

The pump can be set up to divide (accumulate) pulses by a factor of 1 to 999. External Control Analog Programmable 4-20 mA input allows for user defined speed control band; user sets minimum pump speed and maximum speed.

EH-FF Series Electronic Metering Pumps

High Purity Materials PTFE and PFA materials of construction.

Tube Connections Pump tube connections offer maximum installation flexibility.

High Speed Operation Up to 360 strokes per minute results in high-resolution chemical feed, increasing accuracy, eliminating slugfeed effects.

Modular Components
The liquid end, drive and electronics
are modular, enabling economical
repair or replacement of parts.

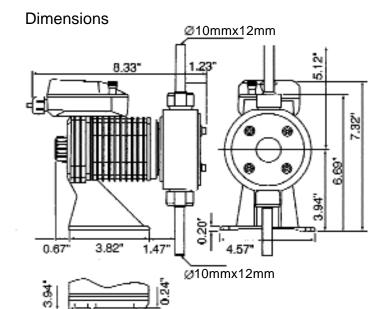
Compact Size Ideal for OEM specifications, EH-FF pumps are small, quiet and light-weight.

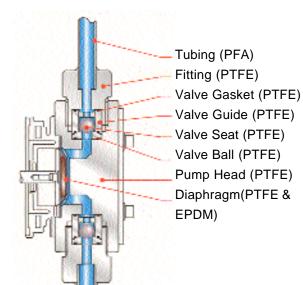
Long Lasting Diaphragm PTFE laminate over EPDM is molded onto a solid core. 2 year warranty with no maintenance.

	Maximum Output Capacity		Maximum Output per	Maximum Pressure		Connection Size
Size	(GPH)	(mL/min)	(stroke mL)	PSI	MPa	Tubing O.D.
C35	4.3	270	0.75	30	0.2	10mm x 12mm
E55	6.7	420	1.17	30	0.2	10mm x 12mm
	C35	Output Size (GPH) C35 4.3	Output Capacity Size (GPH) (mL/min) C35 4.3 270	Output Capacity Output per (stroke mL) C35 4.3 270 0.75	Output Capacity Output per Pres Size (GPH) (mL/min) (stroke mL) PSI C35 4.3 270 0.75 30	Output Capacity Output per Pressure Size (GPH) (mL/min) (stroke mL) PSI MPa C35 4.3 270 0.75 30 0.2

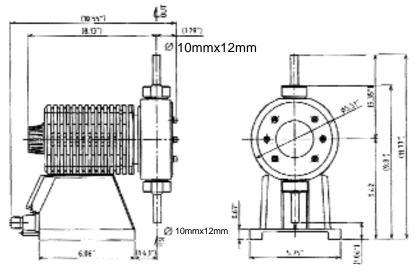
EHC35FF

Materials of Construction



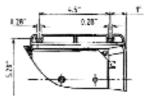


EHE55FF





EN-009X Extension Cable



0.63" 0.39"





Y Module

Iwaki Walchem's World of Sealless Non-Metallic Pumps



High Purity CHEMICAL DELIVERY Pumps



High purity metering pumps, for SEMICONDUCTOR manufacturing



Compact recirculating pumps, for COOLING LOOPS, WET ETCH, COP-PER PLATING, and other applications



High Purity Recirculation pumps for SEMICON-DUCTOR manufacturing

